

EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	157	(photodefinable (photosensitive with (dielectric insulat\$6 polyimide polyamide)) photimag\$6) and ((groov\$6 trench hole opening aperture slot \$6 via pore) same (metal\$8 conduct\$8 aluminum) same (cure cured curing paste ink blad\$6))	FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/08/26 14:53
L2	165	(photodefinable (photosensitive with (dielectric insulat\$6 polyimide polyamide)) photimag\$6) same ((groov\$6 trench hole opening aperture slot \$6 via pore) with (metal\$8 conduct\$8 aluminum) with (cure cured curing paste ink blad\$6))	US-PGPUB; USPAT	OR	ON	2008/08/26 16:56
L3	1	"6559905".pn.	US-PGPUB; USPAT	OR	OFF	2008/08/26 17:24
L4	10048	(imprint\$6 nanoimprint \$6 stamp\$6 print\$6) with (insulat\$6 dielectric) with (trench groov\$6 pattern\$6 preform\$6)	US-PGPUB; USPAT	OR	ON	2008/08/26 17:43
L5	6562	(imprint\$6 nanoimprint \$6 stamp\$6 print\$6) with (insulat\$6 dielectric) with (trench groov\$6 pattern\$6 preform\$6) with (metal \$8 conduct\$8 aluminum cure cured curing paste ink blad \$6)	US-PGPUB; USPAT	OR	ON	2008/08/26 17:45

L6	1326	(imprint\$6 nanoimprint\$6 stamp\$6 print\$6) with (insulat\$6 dielectric) with (trench groov\$6 pattern\$6 preform\$6) with (metal\$8 conduct\$8 aluminum) with (cure cured curing paste ink blad\$6)	US-PGPUB; USPAT	OR	ON	2008/08/26 17:45
L8	10575	257/642.ccls. 257/643. ccls. 257/773.ccls. 257/ e21.585.ccls. 257/ e23.018.ccls. 438/30. ccls. 438/660.ccls. 438/661.ccls. 438/674. ccls. 438/675.ccls. 427/98.4.ccls. 427/357. ccls. 427/360.ccls.	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT	OR	OFF	2008/08/26 17:47
L9	26	L8 and ((imprint\$6 nanoimprint\$6 stamp\$6 print\$6) with (insulat\$6 dielectric) with (trench groov\$6 pattern\$6 preform\$6) with (metal\$8 conduct\$8 aluminum) with (cure cured curing paste ink blad\$6))	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT	OR	ON	2008/08/26 17:47
L10	160	6 and (lcd amlcd (liquid adj crystal adj display))	US-PGPUB; USPAT	OR	ON	2008/08/26 17:59
L11	14	6 same (lcd amlcd (liquid adj crystal adj display))	US-PGPUB; USPAT	OR	ON	2008/08/26 17:59
L12	283	((imprint\$6 nanoimprint\$6 stamp\$6 print\$6) near2 (insulat\$6 dielectric)) with (trench groov\$6 pattern\$6 preform\$6) with (metal\$8 conduct\$8 aluminum) with (cure cured curing paste ink blad\$6)	US-PGPUB; USPAT	OR	ON	2008/08/26 18:03
L13	33	12 and (lcd amlcd (liquid adj crystal adj display))	US-PGPUB; USPAT	OR	ON	2008/08/26 18:03
L14	1	"4508753".pn.	US-PGPUB; USPAT	OR	OFF	2008/08/26 18:15

S1	5	"4336320".pn. "4645733".pn. "5747222".pn. "5716663".pn. "20030108664".pn.	US-PGPUB; USPAT	OR	OFF	2008/08/22 09:20
S2	2	wo-9837133-\$.did.	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT	OR	OFF	2008/08/22 09:21
S3	1	2004wo-ib052105.ap, prai.	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT	OR	OFF	2008/08/22 09:27
S4	1	2005-385692.NRAN.	DERWENT	OR	OFF	2008/08/22 09:27
S5	10566	257/642.ccls. 257/643. ccls. 257/773.ccls. 257/ e21.585.ccls. 257/ e23.018.ccls. 438/30. ccls. 438/660.ccls. 438/661.ccls. 438/674. ccls. 438/675.ccls. 427/98.4.ccls. 427/357. ccls. 427/360.ccls.	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT	OR	OFF	2008/08/25 13:44
S6	254	257/643.ccls.	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT	OR	OFF	2008/08/25 13:47
S7	688	S5 and (photodefinable photosensitive photimag\$6)	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT	OR	ON	2008/08/25 13:48
S8	392	S5 and (photodefinable (photosensitive with (dielectric insulat\$6 polyimide polyamide)) photimag\$6)	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT	OR	ON	2008/08/25 13:50
S9	1319	(photodefinable (photosensitive with (dielectric insulat\$6 polyimide polyamide)) photimag\$6) and (groov\$6 trench hole opening aperture slot \$6 via pore) and (metal \$8 conduct\$8 aluminum paste ink blad\$6)	FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/08/25 13:52
S12	1	"5421926".pn.	US-PGPUB; USPAT	OR	OFF	2008/08/25 15:44

8/26/08 6:16:47 PM

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